

ABSTRACT

A deep layer of a multi-layer disk is accessed in a short time. The moving means is controlled when an objective lens 131 is moved toward a recording surface and it is detected that the level voltage of the focus error signal has reached a slice level voltage H corresponding to displacement of predetermined magnitude from a reference potential E, the objective lens 131 is moved toward the recording surface by a maximum of an upper limit of a predetermined amount of movement and when the amount of movement of the objective lens 131 reaches the predetermined amount of movement, so as to move the objective lens 131 away from the recording surface, and when it is detected during a period of backward movement of the objective lens 131 that the level voltage of the focus error signal has reached the second slice level voltage H corresponding to displacement of predetermined magnitude from the reference potential E, control of beam spot positioning is performed so as to focus an optical spot.